

INFORMATION DISCLOSURE CITATION

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Applicants	Yukiteru MATSUI et al.			
Filing Date	July 16, 2003	Group:	Not Yet Assigned	3723

U.S. PATENT DOCUMENTS							
Examiner Initial*		Document Number	Issue Date	Name	Class	Sub Class	Filing Date if Appropriate
✓VN		6,364,744 B1/	04/02/02	MERCHANT et al.			

FOREIGN PATENT DOCUMENTS							
		Document Number	Publication Date	Country	Class	Sub Class	Translation Yes or No
✓VN		2001-308041/	11/02/01	JAPAN			ABSTRACT

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)	
✓VN	MATSUI, Y. et al., "Chemical Mechanical Polishing Slurry Containing Abrasive Particles Exhibiting Photocatalytic Function", Application Serial No. 10/201,488, filed on July 24, 2002.✓

Examiner <i>Yung van Nguyen</i>	Date Considered 7-23-2004
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